CCMX-ScopeM Advanced Course
2018

Analytical SEM: FIB/SEM

Marco Cantoni
EPFL

Abstract

Modern SEM platforms offer not only a high-resolution over a wide range of acceleration voltages but also range of different detectors. FIB/SEM Focussed Ion beam systems are based on modern high-end SEMs. They combine the SEM imaging with the machining possibilities of a finely focussed ion beam. Micro- and Nano-machining, TEM lamellae preparation are basic tasks which allow shaping an object on a nanometer scale. Combining SEM imaging and FIB machining a FIB/SEM system can take full advantage of the available possibilities when being used as tomography tool.

Contact details

E-mail: marco.cantoni@epfl.ch